REGISTRY includes numerically searchable data for experimental and predicted properties as well as tags indicating availability of experimental property data in the original document. For information on property searching in REGISTRY, refer to:

http://www.cas.org/ONLINE/UG/regprops.html

=>

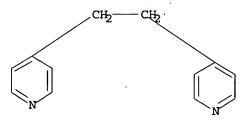
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L1 STRUCTURE UPLOADED

=> d l1

L1 HAS NO ANSWERS

L1 STR



Structure attributes must be viewed using STN Express query preparation.

=> s l1 full

FULL SEARCH INITIATED 16:25:41 FILE 'REGISTRY'
FULL SCREEN SEARCH COMPLETED - 4419 TO ITERATE

100.0% PROCESSED 4419 ITERATIONS

937 ANSWERS

SEARCH TIME: 00.00.01

L2 937 SEA SSS FUL L1

=>

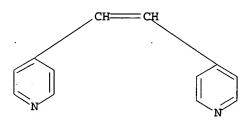
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L3 STRUCTURE UPLOADED

=> d 13

L3 HAS NO ANSWERS

L3 STR



Structure attributes must be viewed using STN Express query preparation.

=> s 13 full

FULL SEARCH INITIATED 16:26:03 FILE 'REGISTRY'
FULL SCREEN SEARCH COMPLETED - 6921 TO ITERATE

٠

100.0% PROCESSED 6921 ITERATIONS

SEARCH TIME: 00.00.01

1506 ANSWERS

L4

1506 SEA SSS FUL L3

=>

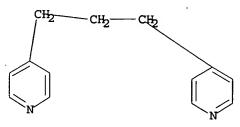
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L5 STRUCTURE UPLOADED

=> d 15

L5 HAS NO ANSWERS

L5 STR



Structure attributes must be viewed using STN Express query preparation.

=> s 15 full

FULL SEARCH INITIATED 16:26:32 FILE 'REGISTRY'

FULL SCREEN SEARCH COMPLETED - 16003 TO ITERATE

100.0% PROCESSED 16003 ITERATIONS

615 ANSWERS

SEARCH TIME: 00.00.02

L6

615 SEA SSS FUL L5

=>

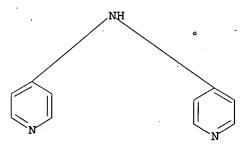
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L7 STRUCTURE UPLOADED

=> d 17

L7 HAS NO ANSWERS

L7 STR



Structure attributes must be viewed using STN Express query preparation.

=> s 17 full

FULL SEARCH INITIATED 16:27:06 FILE 'REGISTRY'

FULL SCREEN SEARCH COMPLETED - 10952 TO ITERATE

100.0% PROCESSED 10952 ITERATIONS

SEARCH TIME: 00.00.01

L8 212 SEA SSS FUL L7

=>

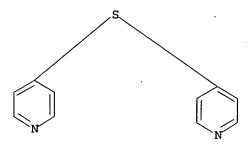
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L9 STRUCTURE UPLOADED

=> d 19

L9 HAS NO ANSWERS

L9 ST



Structure attributes must be viewed using STN Express query preparation.

=> s 19 full

FULL SEARCH INITIATED 16:27:31 FILE 'REGISTRY'
FULL SCREEN SEARCH COMPLETED - 3235 TO ITERATE

100.0% PROCESSED 3235 ITERATIONS

25 TTEDATTONE

212 ANSWERS

257 ANSWERS

SEARCH TIME: 00.00.01

L10 257 SEA SSS FUL L9

=>

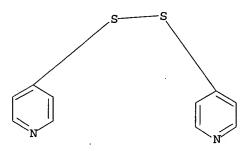
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L11 STRUCTURE UPLOADED

=> d 111

L11 HAS NO ANSWERS

L11 STR



Structure attributes must be viewed using STN Express query preparation.

=> s l11 full · FULL SEARCH INITIATED 16:28:02 FILE 'REGISTRY' FULL SCREEN SEARCH COMPLETED - 542 TO ITERATE

100.0% PROCESSED 542 ITERATIONS

267 ANSWERS

SEARCH TIME: 00.00.01

L12 267 SEA SSS FUL L11

=>

IN Uchigawa, Kyoshi; Komano, Hiroshi

PA Tokyo Ohka Kogyo Co Ltd, Japan

SO Jpn. Kokai Tokkyo Koho, 17 pp.

CODEN: JKXXAF

DT Patent

LA Japanese

FAN.CNT 3

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
ΡI	JP 07199465	A2	19950804	JP 1993-353690	19931229
	JP 3302152	B2	20020715		
	US 6010824	Α	20000104	US 1997-889566	19970708
PRAI	JP 1992-324799	Α	19921110	•	
	JP 1993-77037	A	19930402		
	US 1993-149798	B1	19931110	•	
	JP 1993-353690	A	19931229		•
	US 1994-359640	B3	19941220		
	US 1995-453997	B3	19950530		
	US 1995-477256	B2	19950607	•	
	US 1996-634580	· B2	19960418		

OS MARPAT 124:101857

AB The title resin compns. contain a polymer binder, a monomer having an ethylenic unsatd. double bond, and, as photopolymn. initiators, an acridine compound and ≥1 selected from triazine compds. I, II, and III (R1, R2 = C1-3 alkyl). The compns. show high photosensitivity, resolution, and development margin. Thus, a photosensitive resin composition comprised Fastgen Blue GS, methacrylic acid-Me methacrylate copolymer, trimethylolpropane triacrylate, 9-phenylacridine, and I (R1 = Et).

IT 40047-10-7, 1,3-Bis (9-acridinyl) propane

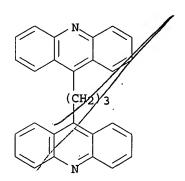
RL: CAT (Catalyst use); USES (Uses)

(photosensitive resin composition containing acridine compound and triazine compound

as photopolymn. initiators)

RN 40047-10-7 CAPLUS

CN Acridine, 9,9'-(1,3-propanediyl)bis- (9CI) (CA INDEX NAME)



L15 ANSWER 9 OF 13 CAPLUS COPYRIGHT 2006 ACS on STN

AN 1995:763709 CAPLUS

DN 124:41402

TI Resist composition

IN Niki, Hiroichi; Hayase, Rumiko; Wakabayashi, Hiromitsu; Shinzato, Naohiko; Oonishi, Kyonobu; Sato, Kazuo; Chiba, Kenji; Hayashi, Yoshio

PA Tokyo Shibaura Electric Co, Japan

SO Jpn. Kokai Tokkyo Koho, 25 pp. CODEN: JKXXAF

DT Patent

LA Japanese

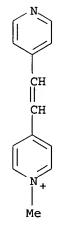
FAN.CNT 2

PATENT NO. KIND DATE

APPLICATION NO.

DATE

SO Jpn. Kokai Tokkyo Koho, 9 pp. CODEN: JKXXAF Patent DT Japanese LΑ FAN.CNT 1 KIND PATENT NO. DATE APPLICATION NO. DATE ______ ---------------19940223 19950905 JP 1994-25041 JP 07234504 A2 PΙ JP 3428715 **B2** 20030722 19940223 PRAI JP 1994-25041 The composition comprises a polymer containing a structural repeating unit I AB (X =cation; n = 0, 1, 2) and a sensitizer containing a cationic group (e.g., quaternary ammonium) in the mol. The composition shows good storage stability and gives high-resolution pattern. The composition is useful for screen plates, color filters, etching resists, etc. 82649-85-2 TT RL: MOA (Modifier or additive use); USES (Uses) (sensitizer; water-soluble photosensitive vinyl alc. ionic resin composition) 82649-85-2 CAPLUS Pyridinium, 1-methyl-4-[2-(4-pyridinyl)ethenyl]-, methyl sulfate (9CI) CN(CA INDEX NAME) CM 1 CRN 46459-24-9 CMF C13 H13 N2



CM 2

CRN 21228-90-0 CMF C H3 O4 S

Me- 0- SO3-

L15 ANSWER 8 OF 13 CAPLUS COPYRIGHT 2006 ACS on STN AN 1995:938451 CAPLUS

DN 124:101857

TI Photosensitive resin compositions using specific photopolymerization initiators

AN 2000:10547 CAPLUS

DN 132:71390

ΤI Photosensitive resin composition containing triazine compound

IN Komano, Hiroshi; Iwai, Takeshi; Ohta, Katsuyuki; Aoyama, Toshimi; Uchikawa, Kiyoshi

PA Tokyo Ohka Kogyo Co., Ltd., Japan

U.S., 26 pp., Cont.-in-part of U.S. Ser. No. 634,580, abandoned. SO CODEN: USXXAM

DT Patent

English LA

FAN.	CNT 3				
PATENT NO.		KIND	DATE	APPLICATION NO.	DATE
ΡI	US 6010824	Α	20000104	US 1997-889566	19970708
	JP 06148885	A2	19940527	JP 1992-324799	19921110
	JP 3187569	B2	20010711		
	JP 06289611	A2	19941018	JP 1993-77037	19930402
	JP 3263172	B2	20020304		
	JP 07199465	A2	19950804	JP 1993-353690	19931229
	JP 3302152	B2	20020715		
PRAI	JP 1992-324799	Α	19921110		·
	JP 1993-77037	Α	19930402		
	US 1993-149798	B1	19931110		
	JP 1993-353690	A	19931229		
	US 1994-359640	B3	19941220	•	
	US 1995-453997	B3	19950530		•
	US 1995-477256	B2	19950607		
	US 1996-634580	B2	19960418		•
~~	MADDAM 120 M1200				

OS MARPAT 132:71390

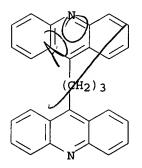
AΒ A photosensitive resin composition useful as a photoresist or for printing plate preparation comprises a polymeric binder, an ethylenically unsatd. monomer, and a photopolymn. initiator. The photopolymn. initiator comprises at least one compound selected from triazine compds. having a bromine atom on the substituted Ph nucleus thereof and trihalomethyl-containing triazine compds. The photosensitive resin composition exhibits a high photosensitivity sufficient for exposure with an argon laser and a satisfactory developability. Addnl. disclosed is a photosensitive resin composition comprising a polymeric binder, a monomer having an ethylenically unsatd. double bond, and photopolymn. initiators including an acridine compound and a triazine compound This second photosensitive resin composition exhibits a high photosensitivity, a high resolution, and a wide development latitude.

IT 40047-10-7

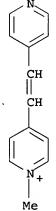
> RL: TEM (Technical or engineered material use); USES (Uses) (photosensitive resin compns. for color filter preparation containing photopolymerizable compds., triazine compds. and)

RN40047-10-7 CAPLUS

CN Acridine, 9,9'-(1,3-propanediyl)bis- (9CI) (CA INDEX NAME)



PRAI JP 1986-113508 19860520 Α JP 1986-138144 19860616 Α B2 19870506 US 1987-47187 A contrast-enhancing layer for a photolithog. material for formation of a AB patterned image (i.e., a resist image) by the light-projection method is comprised of a photobleachable compound having the structural unit represented by the formula I (Z = a divalent group which forms a heterocyclic aromatic ring structure with the N atom; X- = a monovalent anion; n = a pos. integer) and a water-soluble polymer binder. Thus, a Si wafer was coated with a pos.-working photoresist composition (Microposit 1400-27), dried, overcoated with an aqueous solution containing II (a photobleachable compound) and pullulan, dried, exposed to UV (365 nm) radiation through a wafer stepper, and developed to give a line-and-space pattern (0.5 µm width) with clear resolution IT 82649-85-2 113657-69-5 RL: USES (Uses) (photobleachable contrast-enhancing layers containing, for photoresists) 82649-85-2 CAPLUS RNPyridinium, 1-methyl-4-[2-(4-pyridinyl)ethenyl]-, methyl sulfate (9CI) CN (CA INDEX NAME) CM 1 CRN 46459-24-9 CMF C13 H13 N2



CM 2

CRN 21228-90-0 CMF C H3 O4 S

Me- 0- SO3-

RN 113657-69-5 CAPLUS
CN Quinolinium, 1-methyl-4-[2-(4-pyridinyl)ethenyl]-, methyl sulfate (9CI)
(CA INDEX NAME)

CM 1

CRN 113657-68-4 CMF C17 H15 N2 10/664,355 1/23/06, CA Zrg. File, Strice Search, 4/28/00

ANSWER 1 OF 13 CAPLUS COPYRIGHT 2006 ACS on STN L15

AN 2004:1038508 CAPLUS

DN 142:45899

Photosensitive resin composition and its application in forming TΙ photosensitive element, resist pattern, and printed circuit board

Ajioka, Yoshiki; Itagaki, Katsutoshi; Kajiwara, Takuya; Fukaya, Takehiro IN

PA Hitachi Chemical Co., Ltd., Japan

Jpn. Kokai Tokkyo Koho, 19 pp. so

CODEN: JKXXAF

DTPatent

LΑ Japanese

FAN.CNT 1

	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
		-			
ΡI	JP 2004341354	A2	20041202	JP 2003-139446	20030516
PRAI	JP 2003-139446		20030516	•	

MARPAT 142:45899 os

Title composition comprises (A) a binder polymer containing carboxyl group, (B) ABethylenic polymerizable compds., (C) acridine derivs., such as 1,2-bis(9-acridinyl)ethane, and (D) benzotriazole derivs., such as 5-carboxybenzotriazole.

IT62509-62-0

RL: MOA (Modifier or additive use); USES (Uses) (photosensitive resin composition and application in forming photosensitive element, resist pattern, and printed circuit board)

RN62509-62-0 CAPLUS

CNAcridine, 9,9'-(1,2-ethanediyl)bis- (9CI) (CA INDEX NAME)

ANSWER 2 OF 13 CAPLUS COPYRIGHT 2006 ACS on STN L15

2000:772288 CAPLUS AN

DN 133:357238

ΤI Negative-working resist composition

Suetsugu, Masumi; Kusumoto, Takehiro; Takeyama, Naoki; Shinada, Masanori IN ·

Sumitomo Chemical Co., Ltd., Japan PA

SO Ger. Offen., 12 pp.

CODEN: GWXXBX

DTPatent

German LA

Pa	ve	n	+
	_		

FAN.CNT 2

	. 01.1				
	PATENT NO.	KIND	DATE	APPLICATION NO.	DATE
PΙ	DE 10021298	A1	20001102	DE 2000-10021298	20000502
	JP 2001147530	A2	20010529	JP 2000-88790	20000328
	JP 3721931	B2	20051130	•	
	TW 550268	В	20030901	TW 2000-89108000 ·	20000427
	GB 2349479	A1	20001101	GB 2000-10477	20000428

GB 2349479 B2 20010905 20000428 20011211 US 2000-559646 US 6329119 B1 19990430 PRAI JP 1999-124526 Α JP 1999-254630 Α 19990908 The neg.-working UV resist composition comprises an alkaline-soluble polymer, AB an acid-generator, a crosslinking agent, and a base compound represented by general formula I (A = divalent aliphatic hydrocarbon may containing imino, sulfide, or disulfide group; X = N, C(NH2); R1, R2 = H, alky1). The resist composition, suitable for fabricating semiconductor devices, shows excellent resolution, profile, and processing stability. 1135-32-6, 1,2-Di(4-pyridyl)ethylene 4916-57-8, IT1,2-Di(4-pyridyl)ethane 17252-51-6, 1,3-Di(4-pyridyl)propane 37968-97-1, 4,4'-Dipyridylsulfide RL: TEM (Technical or engineered material use); USES (Uses) (base compound in neg.-working resist composition) 1135-32-6 CAPLUS CN Pyridine, 4,4'-(1,2-ethenediyl)bis- (9CI) (CA INDEX NAME)

RN 4916-57-8 CAPLUS CN Pyridine, 4,4'-(1,2-ethanediyl)bis- (9CI) (CA INDEX NAME)

RN 17252-51-6 CAPLUS CN Pyridine, 4,4'-(1,3-propanediyl)bis- (9CI) (CA INDEX NAME)